

ABSTRACT OF THE DISCLOSURE

A substrate treating method for performing a predetermined treatment of substrates as immersed in a treating liquid stored in a treating tank. The method
5 includes a first step of deriving a current treating rate from a relationship between use history and treating rate of the treating liquid and an up-to-date use history of the treating liquid, a second step of determining a corrected treating time by extending a predetermined treating time according to the
10 current treating rate, and a third step of treating the substrates for the corrected treating time.